

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Divisional Patent Application of
Application No. 09/655,833

Takeshi NOGAMI et al

Conf. No. 8708

Application No.: Not Yet Assigned

Art Unit: 2823

Filed: January 20, 2004

Examiner: F.L. Toledo

For: METHOD FOR PRODUCING SEMICONDUCTOR DEVICE, POLISHING
APPARATUS, AND POLISHING METHOD

PRELIMINARY AMENDMENT

MS PATENT APPLICATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 13 of this paper.

Amendments to the Drawings begin on page 23 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 24 of this paper.

An **Appendix** including amended drawing figures is attached following page 24 of this paper.